Special Issue

Advanced Manufacturing of Micro- and Nanotextured Polymer Surfaces

Message from the Guest Editors

The global trend towards miniaturization has been expanding into many areas of human life, enabled by the realization of ever-smaller mechanical, optical, medical, and electronic products. Due to comparably low cost and industrial up-scalability, polymer materials are favorable for the production of surface micro- and nanoscale surface topographies for integrated systems. such as microfluidic devices, micro-optics, and functional surfaces. Polymer micro/nano manufacturing technologies are broadly composed of molding and forming processes as well as additive and subtractive manufacturing processes. This Special Issue is dedicated to recent advances in research and development within the field of advanced manufacturing of micro- and nanotextured polymer surfaces. We are looking for papers that report recent findings and developments in manufacturing technologies and applications for polymeric micro- and nanoscale surface topographies.

Guest Editors

Dr. Nan Zhang School of Mechanical and Materials Engineering, University College Dublin, D04 V1W8 Dublin, Ireland

Prof. Dr. Per Magnus Kristiansen Institute of Polymer Nanotechnology, FHNW University of Applied Sciences and Arts Northwestern Switzerland, Windisch, Switzerland

Deadline for manuscript submissions

closed (31 July 2022)



Micromachines

an Open Access Journal by MDPI

Impact Factor 3.0 CiteScore 6.0 Indexed in PubMed



mdpi.com/si/86333

Micromachines Editorial Office MDPI, Grosspeteranlage 5 4052 Basel, Switzerland Tel: +41 61 683 77 34 micromachines@mdpi.com

mdpi.com/journal/ micromachines





Micromachines

an Open Access Journal by MDPI

Impact Factor 3.0 CiteScore 6.0 Indexed in PubMed



MDPI

About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Editor-in-Chief

Prof. Dr. Ai-Qun Liu

 Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Author Benefits

High Visibility:

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank:

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Rapid Publication:

manuscripts are peer-reviewed and a first decision is provided to authors approximately 17.2 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the first half of 2025).